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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/573,527	03/24/2006	Kiyoshi Kato	0756-7660	5487
31780 ERIC ROBINSON PMB 955 21010 SOUTHBANK ST. POTOMAC FALLS, VA 20165	7590 12/04/2009		<div>EXAMINER</div> <div>WOLDEGEORGIS, ERMILAS T</div>	
			<div>ART UNIT</div> <div>2893</div>	<div>PAPER NUMBER</div>
			<div>MAIL DATE</div> <div>12/04/2009</div>	<div>DELIVERY MODE</div> <div>PAPER</div>

**Please find below and/or attached an Office communication concerning this application or proceeding.**

The time period for reply, if any, is set in the attached communication.

### Office Action Summary

**Application No.**

10/573,527

**Applicant(s)**

KATO ET AL.

**Examiner**

ERMIAS WOLDEGEORGIS

**Art Unit**

2893

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --  
**Period for Reply**

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

**Status**

- 1) ☒ Responsive to communication(s) filed on 22 September 2009.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

**Disposition of Claims**

- 4) ☒ Claim(s) 1-16 is/are pending in the application.
- 4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.
- 5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.
- 6) ☒ Claim(s) 1-16 is/are rejected.
- 7) ☐ Claim(s) \_\_\_\_\_ is/are objected to.
- 8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

**Application Papers**

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on \_\_\_\_\_ is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
- Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
- Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

**Priority under 35 U.S.C. § 119**

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some \* c) ☐ None of:
1. ☒ Certified copies of the priority documents have been received.
  2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
  3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

\* See the attached detailed Office action for a list of the certified copies not received.

**Attachment(s)**

- 1) ☒ Notice of References Cited (PTO-892)
- 2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3) ☒ Information Disclosure Statement(s) (PTO/CDC)
- 4) ☐ Interview Summary (PTO-413)
- 5) ☐ Notice of Informal Patent Application
- 6) ☐ Other: \_\_\_\_\_
- Paper No(s)/Mail Date 11/13/2009

**DETAILED ACTION**

**1. *Continued Examination Under 37 CFR 1.114***

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(c), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(c) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 11/13/2009 has been entered.

**2. *Foreign priority argument:***

Applicant effectively overcomes, 35 U.S.C. §102(e) rejection based on Koyoma et al. (US 2005/0174845 A1), by perfecting foreign priority filing date. The translation and certified copies of the foreign priority documents have been made of record.

**3. *Priority***

Acknowledgment is made of applicant's claim for foreign priority under 35 U.S.C. 119(a)-(d).

**4. *Claim Rejections - 35 USC § 102***

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

5. Claims 1-16 are rejected under 35 U.S.C. 102(b) as being anticipated by Koyama et al. (US. 2002/0126108 A1, hereinafter "Koyama").

In regards to claims 1 and 7, Koyama discloses (Figs. 26(A)-27(B)) a memory device comprising a memory cell (**memory portion, Fig. 27(B)**) formed over an insulating surface (**2602**), which includes a semiconductor film (**2606**) having two impurity regions (**2636/2637**), a gate electrode (**2617/2752**), and two wirings (**2767/2768**) connected to the respective impurity regions (**2636/2637**), wherein the semiconductor film (**2606**) interposed between the two wirings (**2767/2768**) of the memory cell (**memory portion, Fig. 27(B)**) is altered by applying a voltage between the gate electrode and at least one of the two wirings (*since the material used for island shape semiconductor layer of the present application and the Koyama reference are the same: a-silicon, it is the property of this material to alter when applying voltage during operation and/or programming of the device. Therefore, a-silicon exhibits the same property as claimed here*).

In regards to claims 4 and 11, Koyama discloses (Figures 26(A)-27(B)) a memory device comprising a first memory cell and a second memory cell (*though a single memory cell is shown, it is apparent that plurality of memory cells are formed throughout the substrate*) formed over an insulating surface (**2602**), each of which includes a semiconductor film (**2606**) having two impurity regions (**2636/2637**), a gate electrode (**2617/2752**), and two wirings

(2767/2768) connected to the respective impurity regions (2636/2637), wherein the first memory cell comprises an initial state (*inherently there at least one bit to tell whether data is stored or not*); and the semiconductor film (2606) interposed between the two wirings (2767/2768) of the second memory cell (2774) is altered by applying a voltage between the gate electrode and at least one of the two wirings (*since the material used for island shape semiconductor layer of the present application and the Koyama reference are the same: a-silicon, it is the property of this material to alter when applying voltage during operation and/or programming of the device. Therefore, a-silicon exhibits the same property as claimed here*).

In regards to claims 2, 5, 9, 13 and 16, Koyama discloses the memory device (2774) comprises two or more gate electrodes (2617, 2752).

In regards to claims 3, 6, 10, and 14, Koyama discloses the semiconductor film (2606) is altered to an insulating state by applying a voltage between the gate electrode and at least one of the two wirings (*since the material used for island shape semiconductor layer of the present application and the Koyama reference are the same: a-silicon, it is the property of this material to alter when applying voltage during operation and/or programming of the device. Therefore, a-silicon exhibits the same property as claimed here*).

In regards to claims 8 and 12, Koyama discloses the electrode (2617/2752) is interposed between the two wirings (2767/2768).

In regards to claim 15, Koyama discloses (Figures 26(A)-27(B)) a manufacturing method of a memory device, comprising the steps of: forming an island shape semiconductor film (2606) over an insulating surface (2602); forming a gate insulating film (2608) over the island shape semiconductor film (2606); forming a gate electrode (2617) over the gate insulating film (2608); doping an N-type impurity element (Par [0284]) with the gate electrode (2617) used as a mask (Par [0289-0290]), thereby forming an N-type high concentration impurity region (2637/2638) in the island shape semiconductor film (2606); forming an interlayer film (2761/2762) over the gate insulating film (2608) and the gate electrode (2617); forming a contact hole (Par [0298]) in the interlayer film (2761/2762) and a wiring (2767/2768) connected to the high concentration impurity region (2636/2637), thereby forming a memory cell (memory 2774), and applying a voltage between the gate electrode and the wiring of the memory cell, thereby altering a channel region of the island shape semiconductor film to an insulating state (*since the material used for island shape semiconductor layer of the present application and the Koyama reference are the same: a-silicon, it is the property of this material to alter when applying voltage during operation and/or programming of the device. Therefore, a-silicon exhibits the same property as claimed here).*

6.

#### *Correspondence*

Any inquiry concerning this communication or earlier communications from the examiner should be directed to ERMIA WOLDEGEORGIS whose telephone number is

(571)270-5350. The examiner can normally be reached on Monday through Friday 8:30 AM to 6:00 PM E.S.T..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Daveinne Monbleau can be reached on 571-272-1945. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/ERMIAS WOLDEGEORGIS/  
Examiner, Art Unit 2893

*/A. Sefer/  
Primary Examiner  
Art Unit 2893*